10696782_CLS.txt
Most Frequently Occurring Classifications of Patents Returned
From A Search of 10696782 on February 15, 2005

Original Classifications
8 250/492.21
2 250/492.2
2 376/105
2 438/514

Cross-Reference Classifications
4 250/398
3 250/397
3 250/492.2
2 250/281
2 250/305
2 250/423R
2 250/492.21
2 313/361.1
2 313/362.1
2 315/111.41
2 315/505
2 376/120
2 430/599
2 430/600
2 510/276

Combined Classifications
10 250/492.21
5 250/492.2
4 250/397
4 250/398
3 250/423R
2 204/252
2 204/296
2 250/281
2 250/305
2 250/442.11
2 313/359.1
2 313/361.1
2 313/362.1
2 315/111.41
2 315/111.81
2 315/505
2 376/105
2 376/120
2 430/567
2 430/599
2 430/600
2 438/514
2 438/766
2 510/224
2 510/276

Titles of Most Frequently Occurring Classifications of Patents Returned
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10  250/492.21    (8 OR, 2 XR)
        Class   250 :  RADIANT ENERGY
        250/492.1     IRRADIATION OF OBJECTS OR MATERIAL
        250/492.2     .Irradiation of semiconductor devices
        250/492.21    ..Ion bombardment

 5  250/492.2     (2 OR, 3 XR)
        Class   250 :  RADIANT ENERGY
        250/492.1     IRRADIATION OF OBJECTS OR MATERIAL
        250/492.2     .Irradiation of semiconductor devices

 4  250/397       (1 OR, 3 XR)
        Class   250 :  RADIANT ENERGY
        250/396R      WITH CHARGED PARTICLE BEAM DEFLECTION OR
                          FOCUSSING
        250/397       .With detector

 4  250/398       (0 OR, 4 XR)
        Class   250 :  RADIANT ENERGY
        250/396R      WITH CHARGED PARTICLE BEAM DEFLECTION OR
                          FOCUSSING
        250/398       .With target means

 3  250/423R      (1 OR, 2 XR)
        Class   250 :  RADIANT ENERGY
        250/423R      ION GENERATION

 2  204/252       (1 OR, 1 XR)
        Class   204 :  CHEMISTRY:  ELECTRICAL AND WAVE ENERGY
        204/193       APPARATUS
        204/194       .Electrolytic
        204/242       ..Cells
        204/252       ...Diaphragm type

 2  204/296       (1 OR, 1 XR)
        Class   204 :  CHEMISTRY:  ELECTRICAL AND WAVE ENERGY
        204/193       APPARATUS
        204/194       .Electrolytic
        204/279       ..Elements
        204/295       ...Diaphragms
        204/296       ....Organic

 2  250/281       (0 OR, 2 XR)
        Class   250 :  RADIANT ENERGY
        250/281       IONIC SEPARATION OR ANALYSIS

 2  250/305       (0 OR, 2 XR)
        Class   250 :  RADIANT ENERGY
        250/305       ELECTRON ENERGY ANALYSIS

 2  250/442.11    (1 OR, 1 XR)
        Class   250 :  RADIANT ENERGY
        250/306       INSPECTION OF SOLIDS OR LIQUIDS BY CHARGED
                          PARTICLES
        250/440.11    .Analyte supports
        250/442.11    ..With object moving or positioning means

 2  313/359.1     (1 OR, 1 XR)
        Class   313 :  ELECTRIC LAMP AND DISCHARGE DEVICES
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313/359.1 WITH POSITIVE OR NEGATIVE ION ACCELERATION

2 313/361.1 (0 OR, 2 XR)
Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
313/359.1 WITH POSITIVE OR NEGATIVE ION ACCELERATION
313/361.1 .Means for deflecting or focusing

2 313/362.1 (0 OR, 2 XR)
Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
313/359.1 WITH POSITIVE OR NEGATIVE ION ACCELERATION
313/362.1 .Supplying ionizable material (e.g., gas or vapor)

2 315/111.41 (0 OR, 2 XR)
Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS

315/111.01 DISCHARGE DEVICE LOAD WITH FLUENT MATERIAL SUPPLY TO THE DISCHARGE SPACE
315/111.21 .Plasma generating
315/111.41 ..With magnetic field

2 315/111.81 (1 OR, 1 XR)
Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS

315/111.01 DISCHARGE DEVICE LOAD WITH FLUENT MATERIAL SUPPLY TO THE DISCHARGE SPACE
315/111.81 .Electron or ion source

2 315/505 (0 OR, 2 XR)
Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS

315/500 HIGH ENERGY PARTICLE ACCELERATOR TUBE
315/501 .Magnetic field acceleration means
315/505 ..Linear accelerator (Linac)

2 376/105 (2 OR, 0 XR)
Class 376 : INDUCED NUCLEAR REACTIONS: PROCESSES, SYSTEMS, AND ELEMENTS
376/100 NUCLEAR FUSION
376/102 .Inertial confinement (e.g., nuclear explosive)

376/105 ..Particle beam irradiation (excluding photons)

2 376/120 (0 OR, 2 XR)
Class 376 : INDUCED NUCLEAR REACTIONS: PROCESSES, SYSTEMS, AND ELEMENTS
376/100 NUCLEAR FUSION
376/120 .Including bunched particle beam

2 430/567 (1 OR, 1 XR)
Class 430 : RADIATION IMAGERY CHEMISTRY: PROCESS, COMPOSITION, OR PRODUCT THEREOF
430/495.1 RADIATION SENSITIVE PRODUCT
430/564 .Silver compound sensitizer containing
430/567 ..Silver compound having specified crystal form, habit, particle size or particle size distribution

2 430/599 (0 OR, 2 XR)
Class 430 : RADIATION IMAGERY CHEMISTRY: PROCESS, COMPOSITION, OR PRODUCT THEREOF
430/495.1 RADIATION SENSITIVE PRODUCT
430/564 .Silver compound sensitizer containing

430/599 ..Hypersensitizing or latensifying ingredient containing

2 430/600 (0 OR, 2 XR)
Class 430 : RADIATION IMAGERY CHEMISTRY: PROCESS, COMPOSITION, OR PRODUCT THEREOF
430/495.1 RADIATION SENSITIVE PRODUCT
430/564 .Silver compound sensitizer containing
430/599 ..Hypersensitizing or latensifying ingredient containing
430/600 ...Heterocyclic N, O, S, Se, or Te compound containing

2 438/514 (2 OR, 0 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/510 INTRODUCTION OF CONDUCTIVITY MODIFYING DOPANT INTO SEMICONDUCTIVE MATERIAL
438/514 .Ion implantation of dopant into semiconductor region

2 438/766 (1 OR, 1 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR REGION OR OF SEMICONDUCTOR SUBSTRATE
438/765 .By reaction with substrate
438/766 ..Implantation of ion (e.g., to form ion amorphousized region prior to selective oxidation, reacting with substrate to form insulative region, etc.)

2 510/224 (1 OR, 1 XR)
Class 510 : CLEANING COMPOSITIONS FOR SOLID SURFACES, AUXILIARY COMPOSITIONS THEREFOR, OR PROCESSES OF PREPARING THE COMPOSITIONS
510/108 CLEANING COMPOSITIONS OR PROCESSES OF PREPARING (E.G., SODIUM BISULFATE COMPONENT, ETC.)
510/109 .For cleaning a specific substrate or removing a specific contaminant (e.g., for smoker's pipe, etc.)
510/218 ..For equipment used in processing, handling, storing, or serving edible product (e.g., dairy or brewery equipment, household utensils, etc.)
510/220 ...For use in automatic dishwasher
510/224 ....Solid, shaped article (e.g., tablet, briquette, pellet, etc.)

2 510/276 (0 OR, 2 XR)
Class 510 : CLEANING COMPOSITIONS FOR SOLID SURFACES, AUXILIARY COMPOSITIONS THEREFOR, OR PROCESSES OF PREPARING THE COMPOSITIONS
510/108 CLEANING COMPOSITIONS OR PROCESSES OF PREPARING (E.G., SODIUM BISULFATE COMPONENT, ETC.)
510/109 .For cleaning a specific substrate or removing a specific contaminant (e.g., for smoker's pipe, etc.)
510/276 ..For textile material (e.g., laundry detergent, etc.)